

LIST OF REFERENCES CITED BY APPLICANT

(Use several sheets if necessary)



Atty. Docket No.
CH919990030US1 (16316)

Serial No.
09/752,616

Applicant
Michael Bruno, et al.

Filing Date
December 28, 2000

Group
2854

U.S. PATENT DOCUMENTS

EXAMINE R INITIAL*		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLAS S	FILING DATE (if appropriate)
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						

		Foreign Document Number	Date	Country	CLASS	SUBCLAS S	TRANSLATION	
							YES	NO

OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

	A. Bietsch and B. Michel, "Conformal Contact and Pattern Stability of Stamps Used for Soft Lithography", <i>Journal of Applied Physics</i> , Volume 88, Number 7, Pages 4310-4318; 1 October 2000.

EXAMINER

Stephen Fumala

DATE CONSIDERED

9/16/04

* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.